

10/594458

IAP01 Rec'd PCT/PTO 26 SEP 2006

**OLIFF & BERRIDGE, PLC**

ATTORNEYS AT LAW

**Application Data Sheet****Applicant Information**

Applicant Authority type:: Inventor  
 Primary Citizenship Country:: Japan  
 Status:: Full Capacity  
 Given Name:: Hideki  
 Family Name:: SATO  
 City of Residence:: Gunma  
 Country of Residence:: Japan

**Correspondence Information**

Correspondence Customer Number:: 25944

**Application Information**

Application Type:: Regular  
 Subject Matter:: Utility  
 CD-ROM or CD-R:: None  
 Title:: METHOD FOR EVALUATING CRYSTAL DEFECTS OF SILICON WAFER  
 Attorney Docket Number:: 129546  
 Suggested Drawing Figure:: 1  
 Total Drawing Sheets:: 3  
 Small Entity:: No

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Domestic Priority Information			
Application::	Continuity Type::	Parent Application::	Parent Filing Date::
This Application is a	National Phase of	PCT/JP2005/004294	03/11/05

<b>Foreign Priority Information</b>			
Country::	Application Number::	Filing Date::	Priority Claimed::
Japan	2004-095864	03/29/04	Yes
<b>Assignee Information</b>			
Assignee Name::		SHIN-ETSU HANDOTAI CO., LTD.	
Street of mailing address::		4-2, MARUNOUCHI 1-CHOME	
City of mailing address::		CHIYODA-KU	
State or Province of mailing address::		TOKYO	
Country of mailing address::		JAPAN	